

[10191/1616]

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s) : Heribert WEBER et al.
Serial No. : 09/699,704
Filed : October 30, 2000
For : MASS FLOW SENSOR HAVING AN
IMPROVED MEMBRANE STABILITY
Examiner : Lilybett Martir
Art Unit : 2855

TECHNOLOGY CENTER 2800

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REC'D

Commissioner for Patents
Washington, D.C. 20231

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 Jong H. Lee

AMENDMENT

SIR:

In response to the Office Action dated July 5, 2002,
kindly amend the above-identified application as set forth below.

IN THE CLAIMS:

Please amend claims 12 and 13 as follows:

12. (Amended) The mass flow sensor according to claim 9, further comprising:

an oxide layer arranged in the membrane and below the metal layer; and

a recess arranged beneath the nitride layer;

wherein the recess does not contain the oxide layer.

13. (Amended) The mass flow sensor according to claim 3,
wherein:

the nitride layer is formed by an operation selected from the group consisting of a PECVD operation, a LPCVD operation, and a CVD operation.